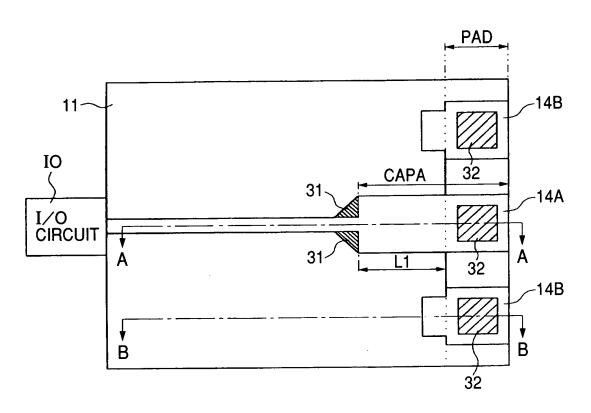
FIG. 1



11: FIRST-LAYER WIRING (FIRST WIRING)

14A: FOURTH-LAYER WIRING (FOURTH WIRING)

FIG. 2

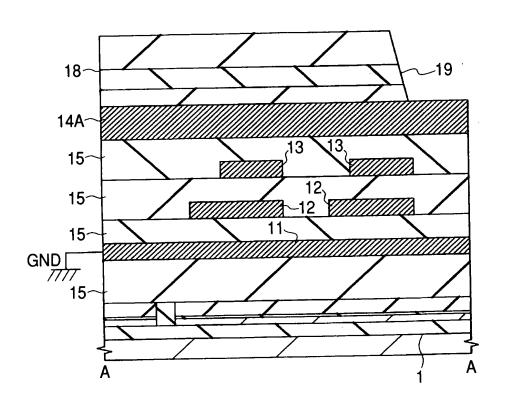


FIG. 3

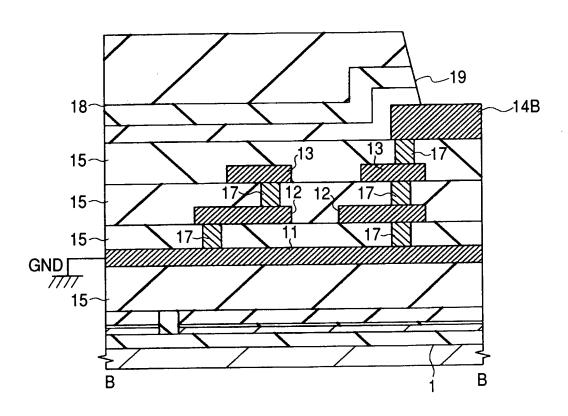


FIG. 4

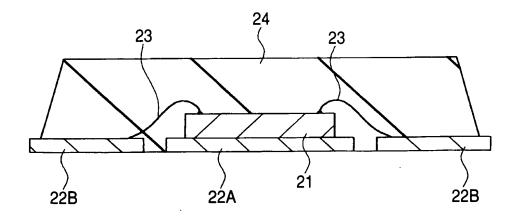
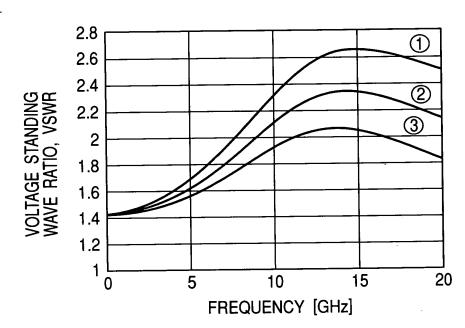


FIG. 5



WIRE INDUCTANCE: 1nH

No.	L	VSWR (≦12GHz)	TRANSMISSION LOSS (≦12GHz)	DECISION	REASON
①	0 μ m	2.7	-0.1dB	×	LARGE VSWR
2	50 μ m	2.4	-0.3dB	0	MOST SUITABLE
3	100 μ m	2.1	-0.5dB	×	LARGE LOSS

FIG. 6

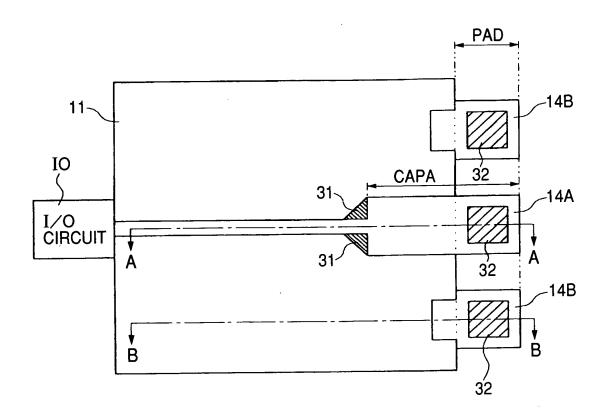


FIG. 7

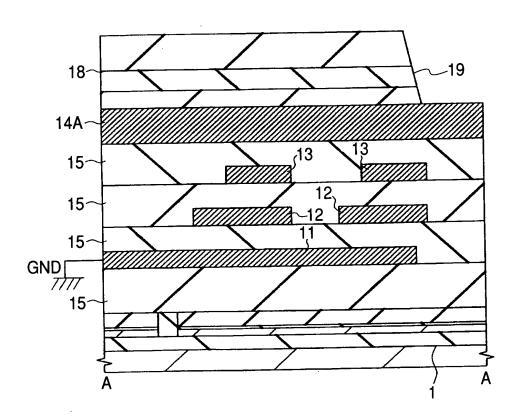


FIG. 8

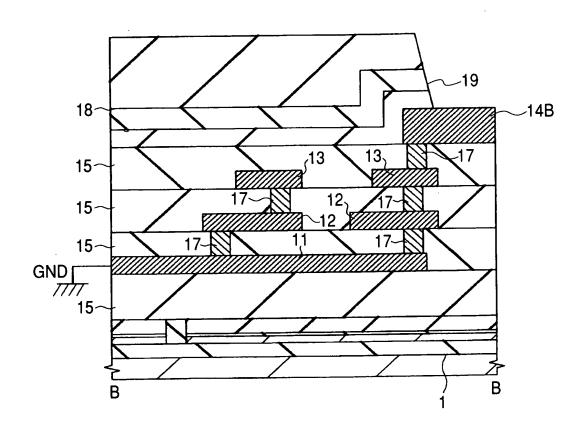


FIG. 9

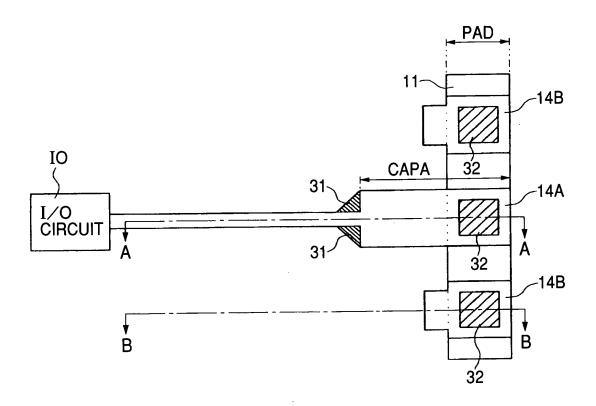


FIG. 10

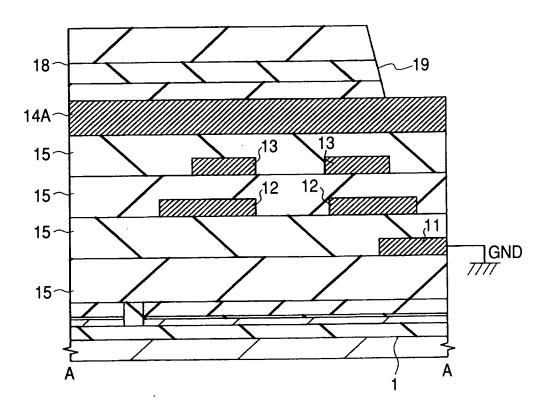


FIG. 11

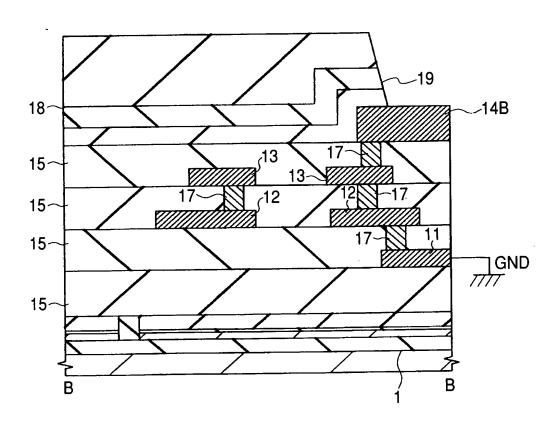


FIG. 12

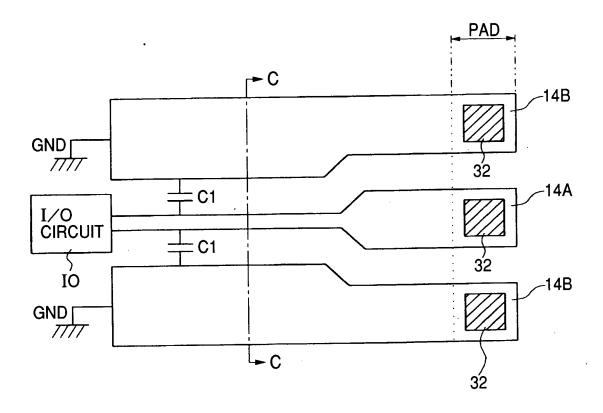


FIG. 13

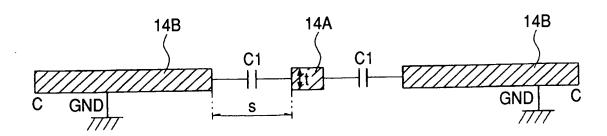


FIG. 14

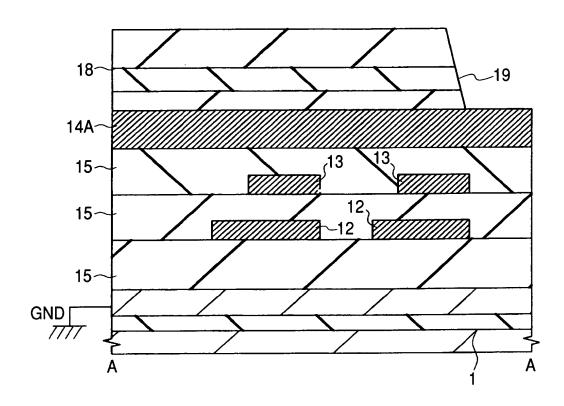


FIG. 15

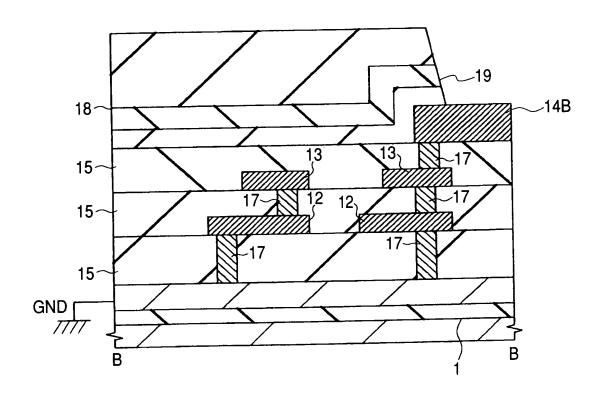


FIG. 16

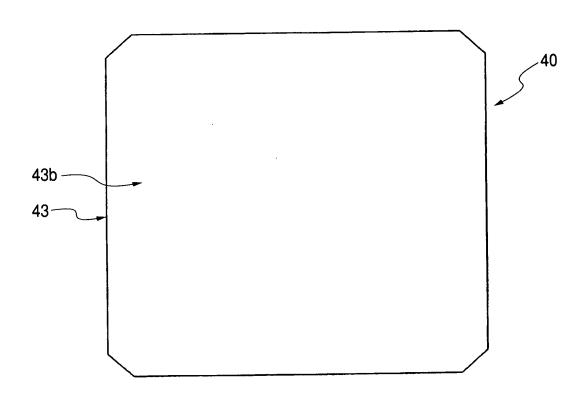


FIG. 17

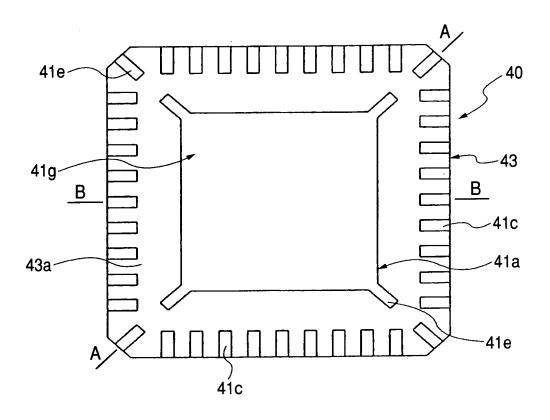


FIG. 18

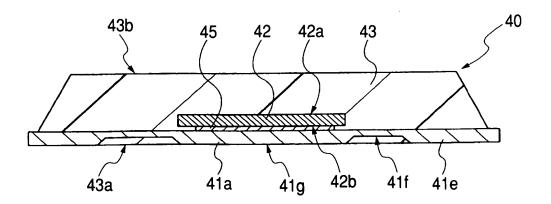
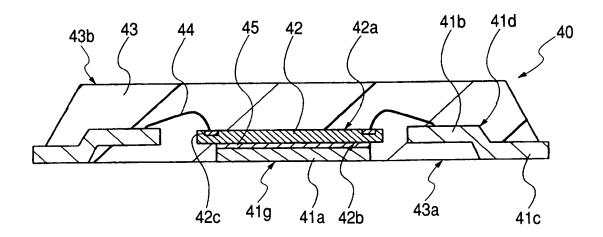


FIG. 19



40: QFN (SEMICONDUCTOR DEVICE)

41a: DIE PAD

41b: INNER LEAD PORTION

41c: OUTER TERMINAL PORTION

41d: LEAD

42: SEMICONDUCTOR CHIP

42a: MAIN SURFACE 42b: BACK SURFACE

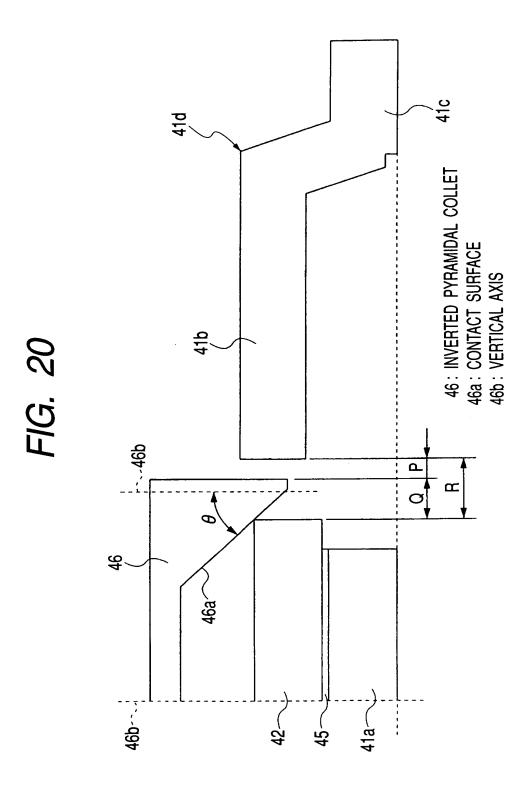
42c: BONDING PAD (ELECTRODE)

43: SEALING MEMBER

43a: MOUNTING SURFACE

43b: SURFACE (OPPOSITE SIDE)

44: BONDING WIRE



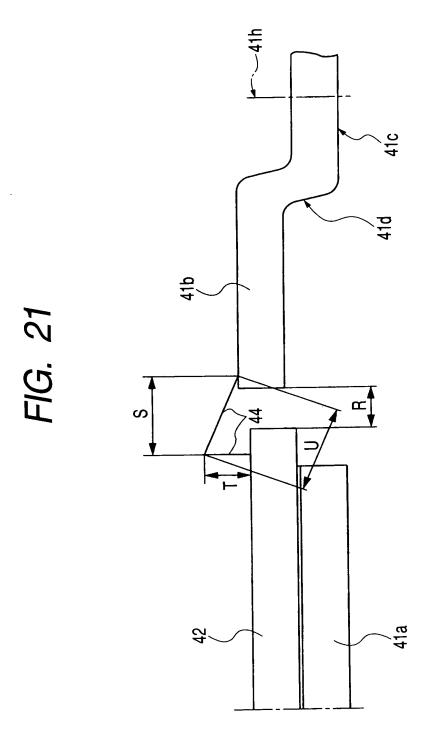


FIG. 22

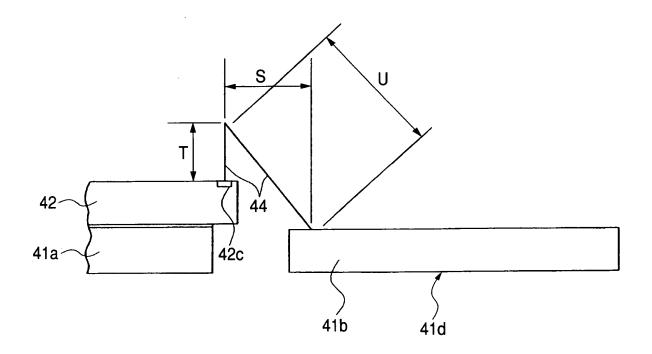


FIG. 23

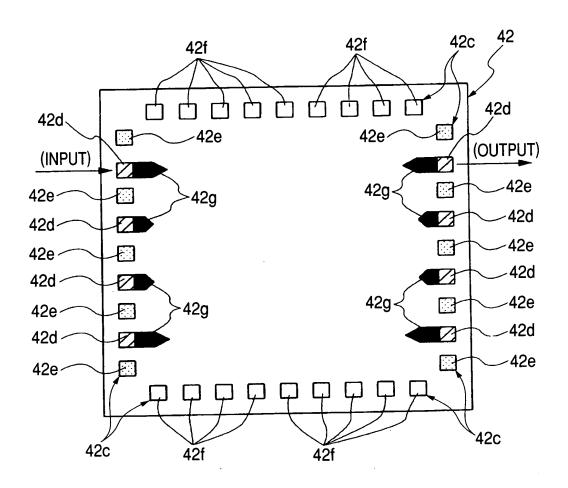
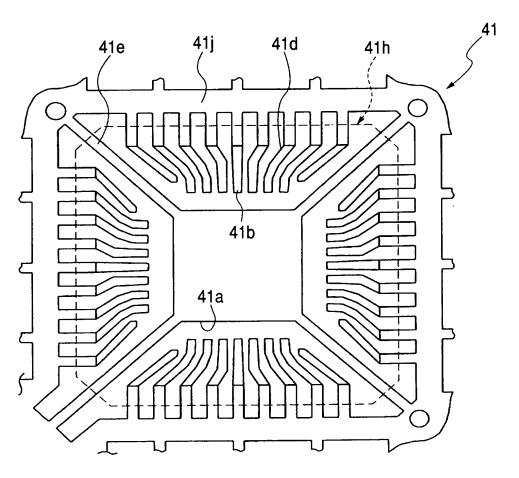


FIG. 24



41: LEAD FRAME

FIG. 25

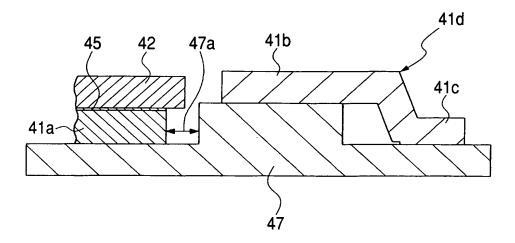


FIG. 26

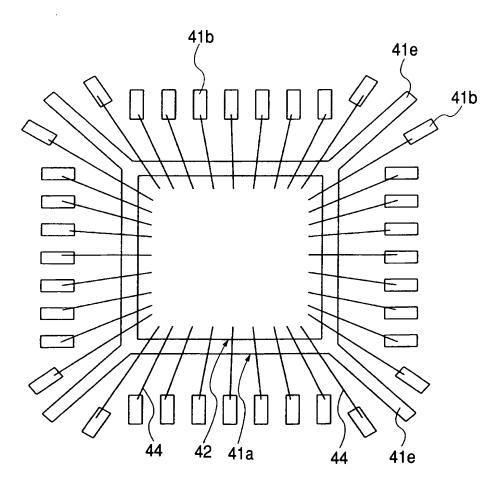


FIG. 27

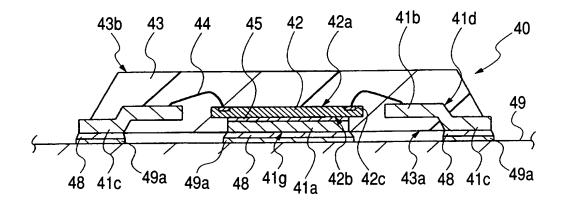
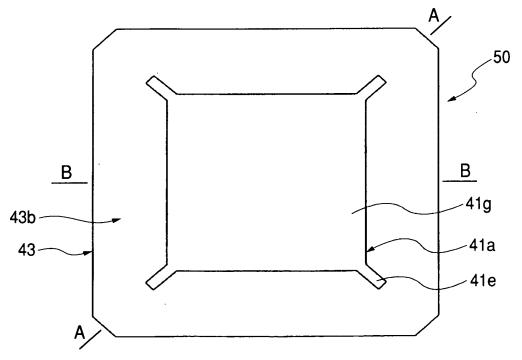


FIG. 28



50: QFN (SEMICONDUCTOR DEVICE)

FIG. 29

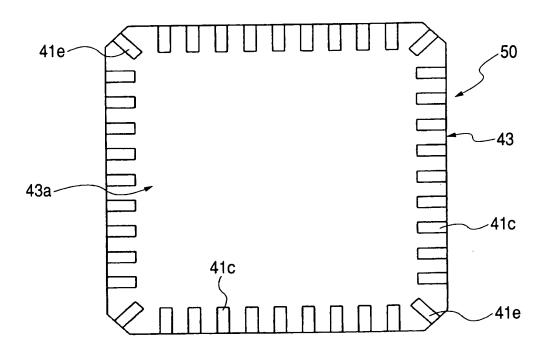


FIG. 30

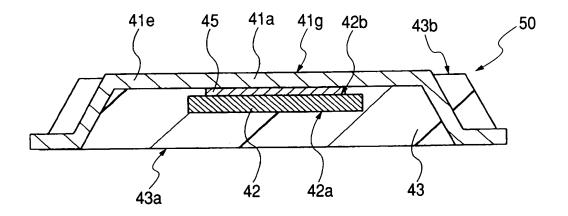


FIG. 31

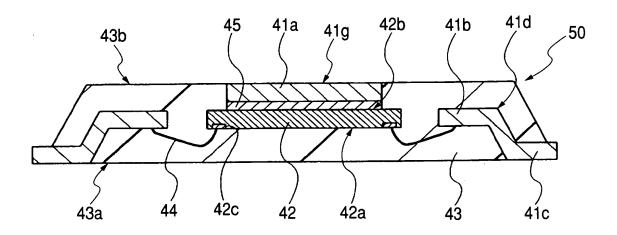
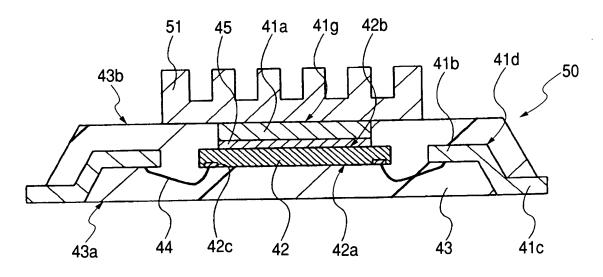
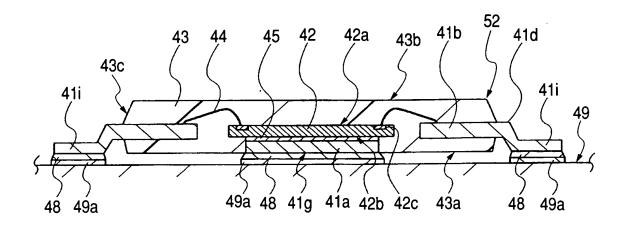


FIG. 32



51: HEAT RADIATION FIN (HEAT SINK)

FIG. 33



41i: OUTER LEAD (OUTER TERMINAL PORTTION)

43c: SIDE FACE

52: QFP (SEMICONDUCTOR DEVICE)